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<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)	<b>Docket Number (Optional)</b> COHL-5410	<b>Application Number</b> 10/065,262
	<b>Applicant(s)</b> Michael J. Scaggs	
	<b>Filing Date</b> September 30, 2002	<b>Group Art Unit</b> 1763

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
RRB	*CA	5,656,186	08/12/1997	Mourou et al.	219	121.69	04/08/1994
↑	*CB	5,800,625	09/01/1998	Engelsberg et al.	134	1	07/26/1996
↓	*CC	6,150,630	11/21/2000	Perry et al.	219	121.68	04/17/1998
✓	*CD	US RE37,585	03/19/2002	Mourou et al.	219	121.69	08/04/1999
RRB	*CE	6,852,946	02/08/2005	Groen et al.	219	121.68	12/20/2002

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
RRB	CF	WO 95/27587	10/19/1995	PCT	B23K	17/22		

**OTHER DOCUMENTS**

(Including Author, Title, Date, Pertinent Pages, Etc.)


<b>Examiner</b> R. B. B.	<b>Date Considered</b> 7-2005
<b>Examiner:</b> Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



**INFORMATION DISCLOSURE CITATION**  
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**COHL-5410**

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**10/065,262**

Applicant(s)  
**Michael J. Scaggs**

Filing Date  
**09/30/2002**

Group Art Unit  
**Unknown**

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	AA	3,679,863	07/25/1972	Houldcroft et al.	219	121 LM	11/10/1969
	AB	3,749,878	07/31/1973	Sullivan et al.	219	121 L	01/19/1971
	AC	4,403,134	09/06/1983	Klingel	219	121 FS	03/17/1982
	AD	4,625,093	11/25/1986	Chryssolouris	219	121 LS	01/24/1986
	AE	4,792,779	12/20/1988	Pond et al.	338	195	04/18/1988
	AF	4,952,771	08/28/1990	Wrobel	219	121.67	12/18/1986
	AG	5,043,556	08/27/1991	Aono et al.	219	121.72	01/08/1990
	AH	5,057,184	10/15/1991	Gupta et al.	156	637	04/06/1990
	AI	5,593,606	01/14/1997	Owen et al.	219	121.71	07/18/1994
	AJ	5,841,099	11/24/1998	Owen et al.	219	121.69	05/17/1996
	AK	5,902,497	05/11/1999	Alber et al.	219	121.63	10/14/1995
	AL	5,902,499	05/11/1999	Richerzhagen	219	121.84	05/22/1995
	AM	5,486,264	01/23/1996	Ghandour	156	635.1	04/22/1994
	AN	5,577,092	11/19/1996	Kublak et al.	378	119	01/25/1995
	AO	5,544,775	08/13/1996	Kerth et al.	216	65	12/22/1994
	AP	5,552,675	09/03/1996	Lemelson	315	111.21	03/10/1992
	AQ	5,593,606	01/14/1997	Owen et al.	219	121.71	07/18/1994
	AR	5,741,559	04/21/1998	Dulaney	427	554	10/23/1995
	AS	5,841,099	11/24/1998	Owen et al.	219	121.69	05/17/1996
	AT	5,968,382	10/19/1999	Matsumoto et al.	219	121.72	07/12/1996
	AU	6,140,655	10/31/2000	Russell et al.	250	492.2	03/24/1999
	AV	6,136,210	10/24/2000	Biegelsen et al.	216	26	11/02/1998
	AW	6,177,358	01/23/2001	Douglas	438	746	12/30/1993
	AX	6,201,212	03/13/2001	Koch et al.	219	121.63	02/13/1998
	AY	6,217,422	04/17/2001	Franca et al.	451	56	01/20/1999
	AZ	6,259,058	07/10/2001	Hoekstra	219	121.75	01/29/1999
	BA	6,294,754	09/25/2001	Nagura et al.	219	121.63	10/29/1999
	BB	6,464,842	10/15/2002	Golovchenko et al.	204	192.13	06/22/2000

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							Yes	No
RRB	BC	10-99978	04/21/1998	Japan	B 23 K	26/00	Abstract	
RRB	BD	59-206189	11/21/1984	Japan	B 23 K	26/00	Abstract	
RRB	BE	WO 03/028941	04/10/2003	PCT	B23K	26/00		
RRB	BF	WO 03/028943	04/10/2003	PCT	B23K	26/12		

**OTHER DOCUMENTS**

(Including Author, Title, Date, Pertinent Pages, Etc.)

RRB	BG	A. Dupont, et al., "Enhancement of material ablation using 248, 308, 532, 1064 nm laser pulse with a water film on the treated surface," <i>J. Appl. Phys.</i> , Vol. 78, No. 3, 1 August 1995, pp. 2022-2028.
RRB	BH	S. Zhu, et al., "Laser ablation of solid substrates in a water-confined environment," <i>Applied Physics Letters</i> , Vol. 79, No. 9, 27 August 2001, pp. 1396-1398.

Examiner <i>R Bunker</i>	Date Considered <i>7-2005</i>
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

<b>INFORMATION DISCLOSURE CITATION.</b> (Use separate sheets if necessary)	Docket Number (Optional) <b>COHL-5410</b>	Application Number <b>10/065,262</b>
	Applicant(s) <b>Michael J. Scaggs</b>	
	Filing Date <b>09/30/2002</b>	Group Art Unit <b>Unknown</b>

### U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
RRB	BI	6,669,774	12/30/2003	Zhang et al.	117	4	07/14/2000
↑	BJ	6,692,337	2/17/2004	Jennings et al.	451	36	03/14/1997
↓	BK	US 2001/0040152	11/15/2001	Higashi et al.	219	121.67	05/02/2001
↓	BL	US 2002/0125232	09/12/2002	Choo et al.	219	121.69	02/28/2002
RRB	BM	US 2003/0129814	07/10/2003	Mizukoshi	438	584	12/27/2002

### FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

### OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

RRB	BN	M. Mosbacher, et al., "Universal threshold for the steam laser cleaning of submicron spherical particles from silicon," <i>Appl. Phys. A</i> , Vol. A 70, (2000), pp. 669-672.
RRB	BO	S. J. Lee, et al., "Shock wave analysis of laser assisted particle removal," <i>J. Appl. Phys.</i> , Vol. 74, No. 12, 15 December 1993, pp. 7044-7047.
RRB	BP	Stephan Roth, et al., "Novel technique for high-quality microstructuring with excimer lasers," <i>Proceedings of SPIE - In Laser Applications in Microelectronic and Optoelectronics Manufacturing V</i> , Vol. 3933, (2000), pp. 338-346.
RRB	BQ	G. Chrysosouris, et al., "Recent Developments in Three-Dimensional Laser Machining," <i>Supplied by the British Library, ICALEO (Inter-national Congress on Applications of Laser and Electro-Optics)</i> , (1990), pp. 281-293.
RRB	BR	J. Sun, et al., "Ultrafast Laser Micromachining with a Liquid Film," <i>ICAEO (Inter-national Congress on Applications of Laser and Electro-Optics)</i> , (2001), 10 Pages in Length.
RRB	BS	Stephan Roth, et al., "Specific Surface Treatment by Laser Irradiation Under Liquid Films," <i>Laser Microfabrication - ICALEO (Inter-national Congress on Applications of Laser and Electro-Optics)</i> , (2000), pp. B-11-B-20.

Examiner <b>R. Bunker</b>	Date Considered <b>7-2005</b>
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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Substitution for form 1449A/PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (use as many sheets as necessary)			<b>Complete if Known</b>		
			Application Number	10/065,262	
			Filing Date	09/30/2002	
			First Named Inventor	Michael J. Scaggs	
			Group Art Unit	1763	
			Examiner Name	Mills, Gregory L.	
			Attorney Docket Number	1443.01	
Sheet	1	of	1		

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Examiner Signature	<i>R Barb</i>	Date Considered	7-2005
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<sup>1</sup> Unique citation designation number. <sup>2</sup> See attached Kinds of U.S. Patent Documents. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup> Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup> Applicant is to place a check mark here if English language Translation is attached.

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